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# Plasma nitridation of aluminized high purity iron

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### Abstract

Surface treatment of high-purity iron by powder liquid coating aluminization and plasma nitridation is investigated with respect to the mechanism of hardening and nitrogen diffusion. Grain boundaries in the aluminized layer are found to be preferentially nitrided in the early stage of nitridation, accompanied by the formation of  $\gamma'$ -Fe<sub>4</sub>N platelets in the substrate. Aluminization and nitridation increase the hardness from HV110–120 for the original  $\alpha$ -Fe(Al) to HV1200–1500 for the modified specimen, which consists of an  $\alpha$ -Fe(Al) matrix with  $\gamma'$ -Fe<sub>4</sub>N and rocksalt AlN. Transmission electron microscopy observation reveals the AlN to be present in the form of platelets of 2–3 nm in thickness with an orientational relationship of  $(001)_{\alpha}/(001)_{AlN}$  and  $[110]_{\alpha}//[100]_{AlN}$  (Baker–Nutting relationship). The kinetics of plasma nitridation is formulated, and good agreement with the experimental results is obtained when first- or second-order reactions are assumed for the formation of AlN under constant N flux at the surface. © 2005 Acta Materialia Inc. Published by Elsevier Ltd. All rights reserved.

Keywords: Plasma nitridation; Aluminization; Iron; Kinetics

## 1. Introduction

The powder liquid coating aluminization technique recently reported by Murakami et al. [1–4], in combination with plasma nitridation, is expected to be a useful surface treatment for die casting machines as protection against severe erosion by molten Al or other liquid metals. The major benefit of such a treatment technique is the ability to treat the internal surfaces that are exposed to these severe environments; in contrast, other protective coatings such as CrN, TiN, and TiAlN films are deposited by physical vapor deposition, a technique that is restricted to external surfaces. The combination of aluminization and nitridation has already been proposed by Tsuji [5,6] and Bindumadhavan [7] for tool steel and carbon steel, and hardnesses of HV1000– 1500 have been achieved for the modified layer. Hardening by steel nitridation is thought to occur through the formation of hard nitrides, resulting in higher internal stress in the matrix, or Guinier–Preston zones. However, the detailed hardening mechanism has yet to be studied in detail for this aluminization and nitridation technique.

In this study, high-purity iron is treated by powder liquid coating aluminization and subsequent plasma nitridation, and the hardened layer is characterized. A diffusion equation for nitrogen is formulated taking

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the formation of nitrides in the aluminized layer into consideration.

### 2. Experimental

High-purity Fe (99.9%) disks were used as substrates. The substrate was polished with abrasive paper to #600 and washed twice with acetone in an ultrasonic cleaning bath for 0.3 ks each time. For powder liquid coating aluminization [4], a slurry was prepared by stirring a mixture of atomized Al powder (under 3 µm in diameter), crushed  $Al_2O_3$  (levigated to 1 µm) and ethanol  $(12.0 \times 10^3 \text{ mm}^3 \text{ for mixed powders of } 1.0 \times 10^{-2} \text{ kg})$ with an impeller at 50 revolutions per second for 0.6 ks. The slurry was pasted onto the disks to a coverage of  $0.50 \text{ mg/mm}^2$ , and the specimens were heated in an oven at 333 K for 1.8 ks to remove ethanol. Each of the prepared disks was then heated in a quartz cylinder by infrared radiation in a vacuum of  $1.3 \times 10^{-3}$  Pa. The temperature was raised at 1.33 K/s, held at 1273 K for 3.6 ks, and then the samples were cooled under  $N_2$  gas flow at about -2 K/s to room temperature.



Fig. 1. Schematic illustration of (a) plane-polishing and (b) XRD measurement.

After the residual powder had been removed with acetone in an ultrasonic cleaning bath, the aluminized substrates were placed in the plasma nitriding chamber. The chamber was evacuated to 1.3 Pa and mixture of Ar and  $H_2$  gas (Ar: $H_2$  = 1:1 by volume) was introduced at an inflow rate controlled by massflow controllers so as to maintain a total chamber pressure of  $1.3 \times 10^2$  Pa. The aluminized substrates were heated to 873 K under direct current (dc) glow discharge to remove the passive oxide surface layer, which prevents effective nitridation. After sputtering for 3.6 ks, gas supply was changed to  $N_2:H_2 = 7:3$ , and the total pressure was maintained at  $3.9 \times 10^2$  Pa. The nitriding temperature was varied from 773 to 873 K, and nitriding was conducted for 3.6-32.4 ks. The specimens were furnace cooled after nitridation. The nitriding conditions are hereafter denoted by TK-tks, and this expression implicitly means that the



Fig. 2. Schematic illustration of specimen preparation for TEM observation: (a) polished and chemically etched plane showing cross-sectional microstructure (left) and the FIB configuration (right); (b) picking of a thin fragment from the molded specimen and mounting on a grid; (c) final thinning.

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